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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-895001	Application No. 10/799,928
<b>Information Disclosure Statement</b> <b>by Applicant</b> (Use several sheets if necessary) (37 CFR §1.98(b))		Applicant Alexander Tregub et al.	
		Filing Date March 12, 2004	Group Art Unit 1711

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Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
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Examiner Signature /Nathan Nutter/ (12/08/2006)	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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Other Documents (include Author, Title, Date, and Place of Publication)		
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NN	BM	Chen, et al., "Pellicle-Induced Reticle Distortion: An Experimental Investigation", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 3546, pp. 167-172 (1998).
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<b>Other Documents (include Author, Title, Date, and Place of Publication)</b>		
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NN	BU	Van Krevelen, D.W., with the collaboration of P.J. Hoftyzer, <u>Properties of Polymers, Their Estimation and Correlation with Chemical Structure</u> , Elsevier Scientific Publishing Company, Amsterdam – Oxford – New York, pp. 68-73 (1976).

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	AK						

Foreign Patent Documents or Published Foreign Patent Applications								
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							Yes	No
	AL							
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	AN							
	AO							
	AP							

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	AR	
	AS	
	AT	

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Substitute Disclosure Form (PTO-1449)